



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

HAMAMATSU, et al.

Serial No.:

10/050,776

Filed:

January 18, 2002

For:

APPARATUS AND METHOD FOR INSPECTING DEFECTS

Group:

2877

Examiner:

M. Stafira

Conf. No.:

9567

<u>AMENDMENT</u>

Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

August 8, 2006

Sir:

In response to the Office Action dated March 8, 2006, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the Claims

Remarks are included following the amendments